

Light Scatter Particulate Emission Monitor

PROCESS & EMISSIONS MONITORING SYSTEMS

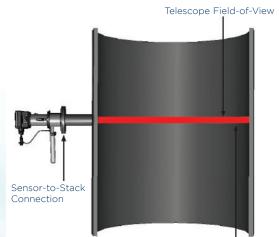
Part of ENVEA's family of Backscatter particulate measurement sensors, the DM 170 is designed to comply with the TUV suitability testing scheme to EN 15267 and for measuring dust concentrations in a wide range of industrial applications.

Due to its wide dynamic range, the DM 170 may be used in Combustion applications as well as in higher dust loading applications (such as Power, Cement and Metals smelting, and in processes without filtration). Its simplicity and wide operating range makes it also ideally suited for process optimisation applications.



DM 170 shown with Manual Audit Unit





Outgoing Laser Beam



CERTIFIED

Tested AMS Regular Surveillance www.tuv.com ID 0000059874



KEY FEATURES:

- ProScatter[™] Backscatter sensor technology with superior minimum detection level as low as 1 mg/m³ compared to conventional techniques
- Manual and remote Zero and Span (Reference) checks available to ensure optimal instrument performance
- Purge Flow Fail Sensor and Optical Shield options
- Non-intrusive system designed to operate in noncondensing stack environments and to reduce the risk of contamination
- Contamination risks are further reduced due to singleside stack installation where critical optical components remain outside the stack
- A Flue Gas Blocker can be fitted to ensure that flue gases do not escape when the unit is opened (for auditing/maintenance purposes), thus enhancing on-site personnel safety
- Offers a more reliable PM dust measurement as an alternative to Opacity and Scintillation based monitors for emissions that are reported in mg/m and provides early indication of increased dust emissions in processes with low dust concentrations

INDUSTRIES AND APPLICATIONS:

The DM 170 is well-suited for use in medium to large stacks and is suitable for low to high dust concentration measurements, regardless of dust velocity or charge. Typical applications include:

- Continuous Emission Monitoring (CEM) relative to Emission Limit Values (ELV) in Power Plant, Boiler and Metal Smelting applications
- Filter performance monitoring in Metal, Mineral and Chemical plants



PRODUCT SPECIFICATIONS

Standard Sensor: up to 250°C (482°F

including flange and cable glands

100 - 240V AC 50/60, 1A

range of dust concentrations

High-temperature sensor: up to 400°C

L 354 x H 216 x B 204 mm (14 x 8.5 x 8 in.),

Single, compact unit (available in a selected

199 102

EMISSIONS & PROCESS MONITORING SYSTEMS

PRINCIPLE OF OPERATION:

SENSOR OPTIONS

Sensor Versions

Sensor Material

Sensor Dimensions

Protection Rating

I/O

Power Supply Voltage

Manual Audit Capability

Automatic Air Purge

Failure Check

Zero/Span Sensor Checks

The DM 170 is based on ENVEA's class-leading *ProScatter™* Backscatter technology. Particles in the stack are illuminated by a laser and the amount of laser-light scattered back from the particles is measured by a detector. Stray scattering and ambient light are eliminated by tuning the instrument's field-of-view and by use of a modulated laser source.

The instrument response is proportional to dust concentration. It can be calibrated to provide a mg/m^3 measurement by comparison to results of a standard reference (isokinetic) test. With the ability to measure dust levels as low as 1 mg/m³, the DM 170 can be used in applications where emissions are well below the sensitivity limit of traditional Opacity instruments.

PROCESS/APPLICATION CONDITIONS Suitable for measurement in non-condensing **Application Suitability** flue gases Outdoor or sheltered use; safe for ambient Location Suitability temperature of -20 to 50°C (-4 to 122°F) -20°C to 250°C (-4°F to 482°F) Flue Gas Temperature option: up to 400°C (752°F) (at monitoring point) Stack Pressure ± 20mbarg Stack Diameter* 1.5 - 15 m (5 - 50 ft) Flue Gas Composition Non-condensing 3" 150 lb ANSI flange DN80 PN10/PN16 flange Stack Connection JIS 100-5k, -10k flange *application specific, please consult ENVEA

752°F)*

Included

24V DC Outputs 1x 4-20mA 2x Alarm relays

Inputs 1x Digital input

Option

with Purge Air Flow sensor (standard on high-temperature sensors)

IP65

316 Stainless Steel

1x RS-485 output

AIR PURGE REQUIREMENTS		
Requires an external supply of 1000 l/min of dry, clean (oil-free) air.		
Туре	Medium Purge Blower	
Power supply voltages (options)	110V AC, 50/60Hz, 7A 230V AC, 50/60Hz, 2.3A	
Blower tubing	3 m (10 ft) hose with fittings (supplied)	
Air Filter	Standard (included)	
Noise pressure level	<80 dBA	
Cable entries	1x M20 cable gland	

MEASUREMENT INFORMATION	
Measurement Type	Light Scattering
Resolution	0.1 mg
Response Time	2 seconds
Dust Levels	<1 to 1000 mg/m³

	ATEX
GAS/DUST ZONE	ZONE 2/22
Certificate number:	PCME 17ATEX0001X
	Outside stack (sensor enclosure) ^A
	Ex nA nC op is IIC T4 Gc
	Ex tc IIIC T120°C Dc
	$Ta = -20^{\circ}C to + 50^{\circ}C$
Certification codes:	Inside stack (sensor body & probe) ^B
	Ex nA nC op is IIC T2 Gc
	Ex tc IIIC T250°C Dc
	$Ta = -20^{\circ}C$ to $250^{\circ}C$
	II 3GD
	Ex nA nC op is IIC T1 Gc
	Ex tc IIIC T400°C Dc
	Ta = -20°C to 400°C
	II 3GD

A See note d) of the ATEX certificate

The probe does not generate heat; therefore, the surface temperature is dependent upon the stack temperature, max. 250 °C or 400 °C (480 °F or 750 °F), depending on the build.

ABOUT ENVEA

As a progressive environmental Company, ENVEA specialises in particulate measurement for industrial processes. With a worldwide reputation for reliability, innovation and technological excellence, the Company produces under the trademark envea™ equipment for concentration and mass monitoring for regulatory, environmental and process control requirements. A dedicated team of qualified application and sales engineers is always on hand and should be consulted in the selection and usage of the most suitable equipment for any particulate application.



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